

**CERTIFICATE OF MAILING BY FIRST CLASS MAIL (37 CFR 1.8)**

Applicant(s): Nosowitz, N., et al

FEB 13 2004

Docket No.

IR 3700 NP

Serial No.

10/706,178

Filing Date

11/12/03

Examiner

not yet assigned

Group Art Unit

not yet assigned

Invention: Composition and Method for Copper Chemical Mechanical Planarization

I hereby certify that this Information Disclosure Statement & attached Info. Disclosure Citation w/ references  
(Identify type of correspondence)

is being deposited with the United States Postal Service as first class mail in an envelope addressed to:

Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

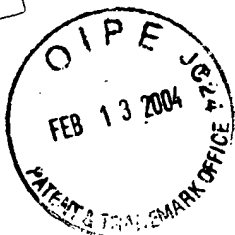
2-11-04  
(Date)

Meleah J. Scott

(Typed or Printed Name of Person Mailing Correspondence)

Meleah J. Scott  
(Signature of Person Mailing Correspondence)

Note: Each paper must have its own certificate of mailing.



PATENT

Attorney Docket No. IR 3700 NP

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Nosowitz, N., et al.

Group Art Unit: n/a

Serial No.: 10/706,178

Examiner: Not yet assigned

Filing Date: 11/12/03

For: Composition and Method for Copper Chemical Mechanical Planarization

**INFORMATION DISCLOSURE STATEMENT**

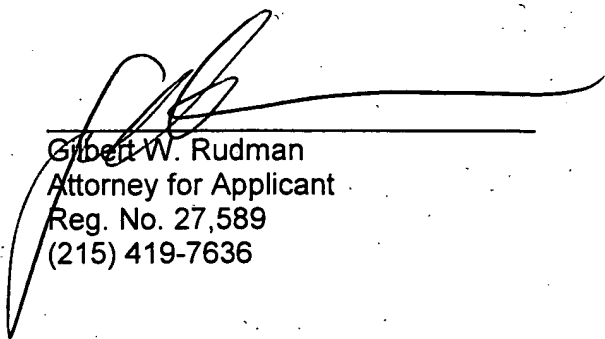
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicant submits herewith a copy of the documents listed on the attached Form PTO-1449.

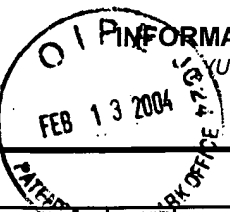
Respectfully submitted,

Date: 2/11/04

  
\_\_\_\_\_  
Gilbert W. Rudman  
Attorney for Applicant  
Reg. No. 27,589  
(215) 419-7636

ATOFINA Chemicals, Inc.  
Patent Department - 26th Floor  
2000 Market Street  
Philadelphia, PA 19103-3222

Encls.

 <p style="margin: 0;">INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)</p>				ATTY DOCKET NO. <b>IR 3700 NP</b>		SERIAL NO. <b>10/706,178</b>	
				Nosowitz, M., et al.			
				FILING <b>11/12/03</b>		GROUP <b>n/a</b>	
<b>U.S. PATENT DOCUMENTS</b>							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
A1	09/091,932		Kaisaki, et al.			6/24/98	
A2	6,117,783	12/12/00	Small, et al.				
A3	4,233,112	11/11/80	Valayil, et al.				
A4	6,117,795	12/12/00	Pasch				
A5	6,068,879	5/30/00	Pasch				
A6	5,073,577	12/17/91	Anderson				
A7	5,177,908	1/12/93	Tuttle				
A8	5,234,867	8/10/93	Schultz, et al.				
A9	5,297,364	3/29/94	Tuttle				
A10	5,486,129	1/23/96	Sandhu, et al.				
A11	5,230,184	7/27/93	Bukhman				
<b>FOREIGN PATENT DOCUMENTS</b>							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
B1	WO/9711484	3/27/97	PCT			✓	
B2	WO/01/44396	6/21/01	PCT			✓	
B3	WO/0112741	2/22/01	PCT			✓	
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	C1	Production of Sulfide Minerals by Sulfate-Reducing Bacteria During Microbiologically Influenced Corrosion of Copper, McNeil, Jones, and Little					
EXAMINER				DATE CONSIDERED			

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

